An FPGA-based Intel 8080 Mockup Soft Microprocessor

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June 22, 2022

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Bibliography

Modules scheme

- Microscopy technique based on the detection of Backascatterd and Secondary ($< 50eV$) electrons by a sample
- Useful in Material and Life Sciences
- Allows characterization of Surface or sub-Surface structure (depending on penetration depth)
- Provides Higher resolution and depth of field than Light Microscopy
- Largely used in Semiconductor Industry

CPU: Instruction Fetch-execute cycle

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CPU: Registers and instructions

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RAM and LCD Display

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Exampe: For loop

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